



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**  
Norio KIMURA et al. : Attorney Docket No. 2001-0660A  
Serial No. 09/864,208 : Group Art Unit 1763  
Filed May 25, 2001 : Examiner Jeffrie R. Lund  
SUBSTRATE POLISHING APPARATUS : **MAIL STOP: AF**  
AND SUBSTRATE POLISHING METHOD

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**AMENDMENT AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE UNDER 37.CFR1.116**  
**EXPEDITED PROCEDURE**  
**EXAMINING GROUP 1700**

Sir:

In response to the Office Action of May 3, 2006, the period for response to which having been extended by two months to October 3, 2006, kindly amend the above-referenced U.S. patent application as follows:

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO BE DEPOSITED  
ACCOUNT NO. 28-6975